## EE-620 Assignment 2 (29-01-2019)

## 1D Poisson numerical simulation:

(1) Perform a 1D numerical simulation of MOSCAP structure with poly Silicon gate (Note: Solve Poisson for entire structure i.e. gate/oxide/ substrate. Choose thickness for gate and substrate such that depletion widths can be easily accommodated). The specifications are:

Substrate doping  $(N_A) = 1e16$ ;  $T_{OX}=5nm$ ;  $N_{Poly}=5e19$ .

Show band diagrams for accumulation, depletion and inversion bias conditions. [15 M]

(2) Obtain LFCV (No oxide and interface traps). Compare it with the one obtained in Assignment 1. [10 M]

(3) For 
$$N_{Poly}$$
= 5e19, vary  $T_{OX}$  (3,5,7 nm) and show the effect on C-V. [10 M]

(4) For 
$$T_{OX}$$
=5nm, vary  $N_{Poly}$  (5e19, 1e19, 5e18) and show the effect on C-V. [10 M]

Following reference might be helpful.

Ref: http://www-device.eecs.berkeley.edu/qmcv/